JUL 1 6 2009

Serial No. 10/567,369 Docket No. PKHF-04053US 2

AMENDMENTS TO THE CLAIMS

Please amend the claims as follow:

- (Previously Presented) A semiconductor layer, comprising:

 a first layer comprising a Ga₂O₃ system single crystal substrate; and
 a second layer obtained by replacing a part rather than all of oxygen atoms of the first layer with nitrogen atoms.
- 2. (Previously Presented) A semiconductor layer according to claim 1, wherein the second layer comprises a GaN system compound semiconductor.
- 3. (Cancelled.)
- 4. (Previously Presented) A semiconductor layer according to claim 1, wherein the first layer comprises Ga_2O_3 , $(In_xGa_{1-x})_2O_3$ where $0 \le x < 1$, $(Al_xGa_{1-x})_2O_3$ where $0 \le x < 1$, $(In_xAl_yGa_{1-x-y})_2O_3$ where $0 \le x < 1$, $0 \le y < 1$, and $0 \le x + y < 1$ as a main constituent.
- 5. (Previously Presented) A semiconductor layer according to claim 2, wherein the second layer comprises GaN, $In_zGa_{1-z}N$ where $0 \le z < 1$, $Al_zGa_{1-z}N$ where $0 \le z < 1$, $In_zAl_pGa_{1-z-p}N$ where $0 \le z < 1$, $0 \le p < 1$, and $0 \le z + p < 1$ as a main constituent.
- 6. (Currently Amended) A semiconductor layer, comprising:
 - a first layer comprising a Ga₂O₃ system semiconductor;
- a second layer comprising a GaN system compound semiconductor and obtained by replacing a part or all of oxygen atoms of the first layer with nitrogen atoms; and
- a third layer comprising [[an]] \underline{a} GaN system epitaxial layer grown on the second layer.
- 7. (Previously Presented) A semiconductor layer, comprising:
 - a first layer comprising a Ga₂O₃ system semiconductor; and
 - a second layer comprising a GaN system compound semiconductor and formed on

Serial No. 10/567,369 Docket No. PKHF-04053US 3

the first layer,

wherein the first layer comprises at least one of $(In_xGa_{1-x})_2O_3$ where 0 < x < 1, $(Al_xGa_{1-x})_2O_3$ where 0 < x < 1, $(In_xAl_yGa_{1-x-y})_2O_3$ where 0 < x < 1, 0 < y < 1, and 0 < x + y < 1.

- 8. (Currently Amended) A semiconductor layer, comprising:
 - a first layer comprising a Ga2O3 system semiconductor;
- a second layer comprising a GaN system compound semiconductor and formed on the first layer; and
- a third layer comprising [[an]] a GaN system epitaxial layer grown on the second layer.
- 9. (Previously Presented) A semiconductor layer according to claim 1, wherein the first layer consists of a single crystal β-Ga₂O₃.
- 10. (Previously Presented) A semiconductor layer according to claim 9, wherein the single crystal β-Ga₂O₃ has a prismatic shape having a square in cross section, and its axis direction matches a-axis <100> orientation, b-axis <010> orientation, or c-axis <001> orientation.
- 11. (Previously Presented) A semiconductor layer according to claim 1, wherein the first layer comprises $(In_xGa_{1-x})_2O_3$ where 0 < x < 1.
- 12. (Previously Presented) A semiconductor layer according to claim 1, wherein the first layer comprises $(Al_xGa_{1-x})_2O_3$ where 0 < x < 1.
- 13. (Previously Presented) A semiconductor layer according to claim 1, wherein the first layer comprises $(In_xAl_yGa_{1-x-y})_2O_3$ where 0 < x < 1, 0 < y < 1, and <math>0 < x + y < 1.
- 14. (Previously Presented) A semiconductor layer according to claim 6, wherein the second layer comprises a same compound semiconductor as the third layer.

Serial No. 10/567,369 Docket No. PKHF-04053US 4

- 15. (Previously Presented) A semiconductor layer according to claim 6, wherein the first layer consists of single crystal β-Ga₂O₃.
- 16. (Previously Presented) A semiconductor layer according to claim 7, wherein the first layer further comprises a single crystal β -Ga₂O₃.
- 17. (Previously Presented) A semiconductor layer according to claim 16, wherein the single crystal β -Ga₂O₃ has a prismatic shape having a square in cross section, and its axis direction matches a-axis <100> orientation, b-axis <010> orientation, or c-axis <001> orientation.
- 18. (Currently Amended) A semiconductor layer according to claim 7, further comprising a third layer comprising [[an]] a GaN system epitaxial layer grown on the second layer.
- 19. (Previously Presented) A semiconductor layer according to claim 8, wherein the second layer comprises a same compound semiconductor as the third layer.
- 20. (Previously Presented) A semiconductor layer according to claim 8, wherein the first layer consists of single crystal β-Ga₂O₃.
- 21. (Previously Presented) A semiconductor layer, comprising: a first layer comprising a Ga₂O₃ system single crystal substrate; and a second layer obtained by replacing a part rather than all of oxygen atoms of the first layer with nitrogen atoms,

wherein the second layer comprises a GaN system compound semiconductor.